IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Woon-Yong PARK, et al.

Art Unit:

To be assigned

Application No.: To be assigned

Examiner:

To be assigned

Filed:

Herewith

Atty. Docket: 6192.0091.D2

For:

PHOTOLITHOGRAPHY METHOD FOR THIN FILM (AS AMENDED)

Preliminary Amendment

Commissioner for Patents Alexandria, VA 22313

Sir:

Please amend the above-identified patent application as follows.

Amendments

In the Title:

Please amend the title to read: -- PHOTOLITHOGRAPHY METHOD FOR THIN FILM ---

In the Specification:

At the beginning of the specification, please enter the following paragraph.

CROSS REFERENCE